**Ali Nawaz - CV**

Ali Nawaz works as a researcher at the Micro Nano Facility, Bruno Kessler Foundation, focusing on the development and optimization of plasma etching processes for silicon-based devices. His role in MNF ranges from designing and refining plasma etch processes to ensuring the quality standards of the processes as well as performing appropriate research to improve existing processes. Today, he will present the basics of wet etching and dry etching methods from a technological point of view.